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## nSpec Version 0.23.0.4

Release Date: 18 Oct 2023

**Documentation Updated: 27 Nov 2023** 

## Overview

This patch release fixes bugs found in nSpec v0.22.0.0 and v0.23.0.1. One of the bug fixes has been resolved through the addition of a new program option.

## Upgrading to v0.23.0.4

Library Update Not Required

If upgrading from a version more than 1 release prior, please reference all intermediate release notes for upgrade steps *for each version*.

# **Bug Fixes**

### **Highlights**

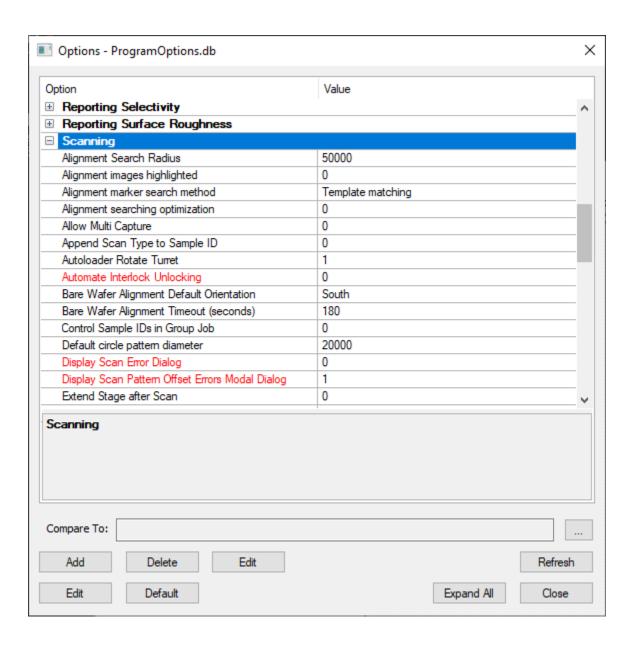
NSPEC-6043: "Scan Pattern Exceeds..." pop-up blocks cassette production flow when using Bare Wafer Alignment

A "Scan Pattern Exceeds Stage X maximum by 0.000000 microns" message pops up on every wafer when running a wafer scan, wafer cassette job, loop job, or loop scan when the pattern offset is set to 0 for X and Y. A new Program Option **Display Scan Pattern Offset Errors Modal Dialog** can be set to prevent this message from popping up and disrupting the scan.

This new option defaults to 1, which allows the above blocking popup to display, and allows the operator to respond accordingly. If set to 0, the blocking modal dialog will **not** display and the scan will continue without disruption, with the calculated offset and error written to the log.

The Display Scan Pattern Offset Errors Modal Dialog option can be found under the Scanning tab.





## Changelog

Т	Key	Release Notes Summary	Affected Releases
	NSPEC- 6043	"Scan Pattern Exceeds" pop-up blocks cassette production flow when using Bare Wafer Alignment	0.22.0.0
	NSPEC- 7657	No error message when scan exceeds stage bounds	0.23.0.1

#### 2 issues